

Figure 1. Conventional CW etch process results in around 15nm RIE lag.

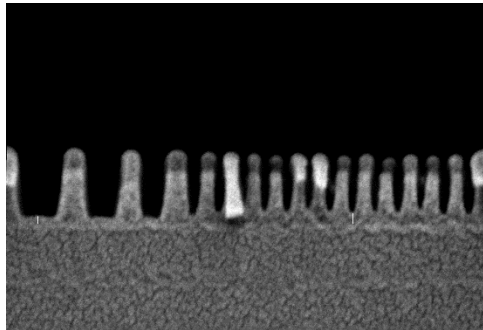


Figure 2. Q-ALE process results in nearly no RIE lag.

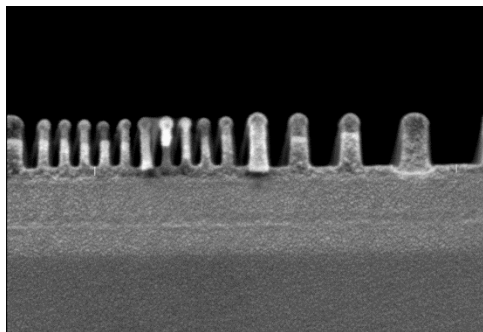


Figure 3. Combination of CW etch and Q-ALE process results in less than 5nm RIE lag.